

1 **Asymmetric transition of electrical resistance in an all-solid-state**
2 **redox device with Fe₃O₄ and Li-ion electrolyte thin films for**
3 **physical reservoir computing**

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10 In recent years, ion-gating devices have been used in artificial neuromorphic computing and
11 achieved high performance for time-series data processing. However, the origin of such
12 performance still needs to be clarified. In this study, we fabricated an all-solid-state redox
13 device with functional material Fe₃O₄ and Li-ion conducting solid electrolytes, and the
14 transient response of the electrical resistance of the Fe₃O₄ thin film to time-series data input
15 was investigated. The transition between high and low electrical resistance states was
16 asymmetry, and residual Li-ion in the thin film led to a hysteresis effect. These unique
17 features, which is induced by ion-electron dynamics coupling, contributes to the high
18 performance of physical reservoir computing utilizing ion-gating device.

19

1. Introduction

There is a strong demand to develop artificial intelligence devices to process information that increases explosively and efficiently. Several studies have been recently conducted to realize artificial neural network systems that can process various information on terminal devices using physical devices.¹⁻⁷⁾ Recently, reservoir computing, which can process time series data with a small learning cost, has been attracting attention, and attempts to process time series data with high accuracy using nonlinear responses and short-term memory of physical devices have been vigorously pursued.⁸⁻²⁶⁾ Among these, an all-solid-state ion-gating device, which is one of the ionic devices,²⁷⁻³⁶⁾ can control the physical properties (not only electrical properties but also magnetic and optical properties) of functional materials by transporting ions,³⁷⁻⁵³⁾ and the modulated electrical properties can be used in artificial neural networks and artificial retina.⁵⁴⁻⁵⁹⁾ It has been demonstrated that ion-gating performs highly in image recognition and time series data prediction tasks.²²⁻²⁴⁾ However, the origin of the high performance needs to be clarified, and the details of the internal state change of the functional material in response to time series data input, which is converted to voltage, need to be investigated. In ion-gating, electronic carriers are injected into the functional material via charge compensation along with the transport of ions.^{33-35,37-43,45-53)} Therefore, measuring electrical resistance is a powerful probe method to understand the internal state of functional materials. Herein, we fabricated an all-solid-state reduction/oxidation (redox) device by stacking a functional material and a solid electrolyte and focused on the transient response of the electrical resistance of the functional materials to time-series data input duration to clarify changes in the internal state (i.e., electrical resistance) of the functional materials.

In this study, we adopted Fe₃O₄, which is known to operate as an artificial neural network device as well as to control the electrical and magnetic properties (magnetization and magnetization direction) of Fe₃O₄ to a large extent by voltage when combined with a solid electrolyte, for a functional material.^{43,48,60-62)} Lithium-ions in the solid electrolyte diffuse into the lattice of Fe₃O₄ by applying voltage, and such inserted ions modulate a number of electronic carriers ($>10^{21}$ cm⁻³) in Fe₃O₄ thin film.^{43,48, 63)} Since Li-ions are driven by the electric field that depends on the series resistance of the Fe₃O₄ thin film and the solid electrolyte, it was found that by inputting time series data consisting of random voltages, the effective electric field to Li-ion is modulated by the electrical resistance of Fe₃O₄ that

1 changes sequentially and shows various transient responses.

2

3 **2. Experimental methods**

4 A 12-nm-thick magnetite thin film was deposited on a flat surface of a MgO (110) substrate
 5 by pulsed laser deposition (PLD) using a magnetite polycrystalline target. The area of the
 6 thin film was $500 \times 700 \mu\text{m}^2$. The base pressure in the deposition chamber was 3.3×10^{-5} Pa.
 7 The substrate temperature was kept at 573 K, A flow rate of the Ar (99 %) and O₂ (1%)
 8 mixture gas was fixed at 0.2 sccm, and the pressure was kept at 1.3×10^{-3} Pa during
 9 deposition.⁴⁸⁾ A 5-nm-thick Ti adhesion layer and 50-nm-thick Pt electrode with a Hall-bar
 10 shape were continuously deposited on the magnetite thin film by rf magnetron sputtering.
 11 Then, A Li₂O-SiO₂-ZrO₂ (LSZO) thin film was deposited by PLD, using a Li-excess LSZO
 12 ceramic target, in a 3.4 Pa O₂ atmosphere at a flow rate of 8.5 sccm. Finally, the Au gate
 13 electrode was deposited on the LSZO electrolyte by rf magnetron sputtering. Metal shadow
 14 masks were used to pattern each layer.

15 A micro-Raman spectroscopy, which has incident light with a wavelength of 573
 16 nm and a power of 0.5 mW to avoid thermal oxidation, was used to evaluate the quality of
 17 the magnetite thin film. The exposure times and accumulation were set to 120 seconds and
 18 20 times.

19 Electrical measurement was performed on the device in a high vacuum chamber ($<$
 20 10^{-3} Pa) using a Keithley 4200-SCS parameter analyzer. Five pulse trains with different pulse
 21 periods (50, 75, 100, 150, and 200 seconds) were prepared to investigate responses to various
 22 inputs. Each pulse train had a base voltage of 1.0 V and an amplitude range of [0.5, 1.5 V].
 23 Five pulse trains were input one by one with time intervals in between. Drain current I_D was
 24 set to 3 μA during the measurement, and voltage drop V_{XX} was acquired as information on
 25 electrical resistance modulated by ion-gating. The following equation was used to calculate
 26 the relaxation time τ .⁵⁷⁾

$$27 \quad V_{XX} = A \exp \left[- \left(\frac{t-t_0}{\tau} \right) \right] + V_{\infty} \quad (1).$$

28 where A , t , t_0 , and V_{∞} denote the amplitude of V_{XX} response, retention time, the pulse-on
 29 finished time, and the base level of V_{XX} at the corresponding pulse-on period.

30

3. Results and discussion

3.1 Results

Figure 1(a) shows a schematic illustration of a fabricated device consisting of a magnetite channel, electrodes for electrical measurement, LSZO electrolyte film, and gate electrodes. Raman peaks, which are located at 669 cm^{-1} , 542 cm^{-1} , and 310 cm^{-1} , of the magnetite thin film were assigned by A_{1g} , $T_{2g}(2)$, and $T_{2g}(3)$, and there is no impurity (e.g., FeO , Fe_2O_3 , and so on), as shown in Fig. 1(b).^{43,48)} Figure 1(c) shows a transmission electron microscope (TEM) image of cross-section of a fabricated device and its fast Fourier transformation (FFT). It was successfully confirmed that the thin film was grown epitaxially on the surface of MgO (110) substrate.⁴⁸⁾

The electrical property of said device was evaluated by measuring drain current I_D , which was modulated by gate voltage V_G sweeping, as shown in Fig. 2(a). I_D flowing in the channel thin film was enhanced as V_G increased from 0.0 V to 2.0 V, resulting from electronic carrier doping induced by Li-ion migrating to the Fe_3O_4 side. On the other hand, I_D was reduced as V_G decreased from 1.0 V to 0.0 V, resulting from removing the electronic carrier induced by Li-ion migrating to the gate electrode side. On this I_D modulation, large hysteresis was observed due to relatively slow migration in the Fe_3O_4 , indicating that Li-ion was inserted in and deserted from Fe_3O_4 . Here, magnetite has 24 Fe ions, which are 8 tetrahedral Fe ions (Fe_{8a}) and 16 octahedral Fe ions (Fe_{16d}), and 32 O ions (O_{32e}) in a unit cell. Li-ion inserted in the magnetite is located at the 16c site, which has an octahedral vacant center surrounded by 6 oxygen ions, as shown in Fig. 2(b).⁶⁴⁾ While Fe_{8a} ion is trivalent and has five down-spins in d orbit, Fe_{16d} ion has a mixed valence state due to the co-existence of trivalent and divalent Fe ions, and trivalent Fe ion has five up-spins and divalent Fe ion has a down-spin in addition to five up-spins. Down spin at Fe_{16d} contributes to electrical conduction.⁶⁵⁾ Thus, when the I_D was enhanced (reduced), electron was doped (removed) in trivalent (divalent) Fe_{16d} through reduction (oxidation), increasing the number of down-spin of Fe_{16d} .⁴³⁾ Such electronic carrier tuning induced by insertion and desertion of Li-ion showed large hysteresis with slow relaxation. This hysteresis effect indicates that the present state has information based on the past state induced by input at the past step.^{23,24)} We will examine how this hysteresis affects the dynamics of ions and electrons during input of the random wave used in the time-series data processing task.

1 Figure 3(a) shows a measurement configuration of V_{XX} response in proportion to
 2 electrical resistance for time-series data inputs. A time-series voltage has a pulsed shape with
 3 50 steps and is input as V_G . I_D was fixed at 3 μA , and potential drop V_{XX} was acquired during
 4 the V_G inputs. The horizontal axis of the V_{XX} signal was normalized to compare the shape of
 5 the signals measured at various pulse periods. Figure 3(b) shows the V_{XX} response for the
 6 V_G input in a cropped region of normalized time, corresponding to a time step k , ranging
 7 from 559 to 579. Here, k is a pulse period with pulse-on and pulse-off. As the pulse period
 8 of V_G was extended, the degree of modulation in V_{XX} became larger since the amount of
 9 doped electronic carrier was increased during its application time. Then, V_{XX} decreased
 10 while maintaining said trend in the pulsed-off interval. In addition to such modulation rate
 11 variation at various pulse periods, we evaluated the relaxation time of V_{XX} response under
 12 pulse voltage application. Figures. 3(c) and 3(d) show relaxation time variations in pulse-on
 13 and pulse-off durations at various k . Although relaxation time in pulse-on duration was
 14 longer than that in pulse-off duration (asymmetric transient response of V_{XX} at each k) in the
 15 entire range, the relaxation times of both durations increased as the pulse period extended.
 16 Furthermore, relaxation time variation resulted from the input of time-series voltage, and it
 17 was found that the relaxation time of electronic carrier tuning, induced by ion and electron
 18 migrations, positively correlates with the amplitude of voltage input. Thus, an ion-gating
 19 device shows a non-single transient response with various relaxation times by the input with
 20 various intensities, and a variety of outputs can be obtained by inputting the time-series
 21 voltage.

22 Fig. 4(a) shows the V_{XX} response for input pulse voltages train in a cropped region
 23 of normalized time ranging from 750 (time step of k_{39}) to 850 (time step of k_{42}) to investigate
 24 a detail of relaxation time, which depends on input amplitude. The difference is that the
 25 amount of change in V_{XX} was more significant as the pulse period became longer and resulted
 26 from the more considerable amount of tuned electronic carrier density due to the longer
 27 application time of V_G . V_{XX} amplitude variation at each k was not in good agreement with
 28 input amplitude variation, shown as red and blue dashed lines described in the figures for
 29 pulse-on and pulse-off. This inconsistency results from said asymmetric transition response,
 30 induced by ion-gating, of the electrical resistance state. Those relaxation times in pulse-on
 31 and pulse-off durations are plotted in the upper and lower panels of Fig. 4(b). The extension

1 of the pulse period not only lengthened the relaxation time but also changed the shape of the
 2 k -dependence of the relaxation time as follows. For a pulse-on time, the variation of
 3 relaxation time was slight for short pulse periods of 100 seconds or less, but the variation of
 4 relaxation time increased for more extended pulse periods of 150 seconds or more, as shown
 5 in an upper panel of Fig. 4(b). Then, the relaxation time of k_{39} was considerably expanded,
 6 and the variation of relaxation time after k_{40} became small, as shown in the upper panel of
 7 Fig. 4(c).

8 On the other hand, the change in the distribution of relaxation times for pulse-off
 9 duration was different from that of the pulsed-on one, as shown in a lower panel of Fig. 4(b).
 10 While up-turn convexity was shown below shorter intervals of 75 seconds, down-turn
 11 convexity was shown above longer intervals of 150 seconds via approximate flat distribution
 12 at the interval of 100 seconds. This is because the increase in relaxation time at k_{40} was
 13 smaller than those at other k s, as shown in a lower panel of Fig. 4(c). From these results,
 14 dynamics driven by voltage application in ion-gating devices showed the asymmetric
 15 transition between high V_{XX} and low V_{XX} states.

17 3.2 Discussion

18 Here, we discuss the origins of asymmetric transition between high V_{XX} and low
 19 V_{XX} states. Figure 4(d) shows schematic illustrations of transitions between the low electrical
 20 resistance (R) state and the high R state of the channel of the ion-gating device. Ion-gating
 21 leads to R modulation of the Fe_3O_4 thin film through redox reaction. The Fe_3O_4 thin film
 22 possesses a large amount of Li-ions in its lattice in a low R state, and those Li-ions are
 23 removed from the lattice by V_G application.^{43,48)} The Li-ion was driven by an electric field,
 24 and the electric field depends on R of the thin film (R_C) and R of the solid electrolyte (R_{SE}).
 25 This is because the electrical equivalent circuit between the gate and source electrodes is
 26 described as a series circuit of R_C and R_{SE} . Here, the total R (R_{total}) can be described as
 27 follows:

$$28 \quad R_{\text{total}} = R_C + R_{SE}, \quad (2)$$

29 Moreover, voltage potential between gate and source electrodes (i.e., V_G) is expressed using
 30 eq. (2) as shown below,

$$31 \quad V_G = I_G R_{\text{total}} = I_G (R_C + R_{SE}). \quad (3)$$

1 Then, eq. (3) can be transformed as follows.

$$2 \quad I_G = \frac{dQ}{dt} = \frac{V_G}{(R_C + R_{SE})}, \quad (4)$$

3 where I_G and Q denote electrical current flowing in the equivalent circuit, and the amount of
 4 electrical charge, which corresponds to Li-ion of the solid electrolyte and electronic carrier
 5 modulated by redox reaction, and dQ/dt shows the amount of flowing Q per a unit of time t .
 6 When R_C is reduced by V_G application, I_G and dQ/dt become large since V_G and R_{SE} are
 7 constants. In short, the effective electric field affecting Li-ion varied with the R_C state and
 8 said the electric field was large (small) when R_C was low (high) by Li-ion insertion
 9 (desertion) due to a slight potential drop in the Fe_3O_4 and a significant potential drop in the
 10 solid electrolyte. This variation in the electric field leads to variation in the transition speed
 11 of the R_C state, meaning that the transition from low R_C to high R_C is faster, and the transition
 12 from high R_C to low R_C is slower. This is the origin of asymmetric transition response of V_{XX} .
 13 Furthermore, some of the inserted Li-ions remained in the thin film, resulting in the
 14 inconsistency between V_{XX} amplitude and input amplitude in Fig. 4(a). These ions contribute
 15 to the hysteresis effect observed in the V_{XX} response for time-series V_G input. This study
 16 found that ion-gating leads to electronic carrier density modulation accompanied by unique
 17 features, such as asymmetric transition and hysteresis effect. These are critical features for
 18 implementing physical reservoir computing, which requires nonlinearity (asymmetric
 19 transition response) and short-term memory (hysteresis effect).²²⁻²⁴⁾

20

21 **4. Conclusions**

22 We fabricated an all-solid-state redox device with Fe_3O_4 and Li-ion electrolyte thin films
 23 and measured the V_{XX} response of the said device under a random V_G train input to
 24 investigate the origin of a performance as an artificial neuromorphic device through the
 25 internal state (i.e., electrical resistance) of the Fe_3O_4 thin film. It was found that the transition
 26 of *the R* state was asymmetric, and the information of V_G input at the past step remained as
 27 residual Li-ions in the thin film. This asymmetric behavior and hysteresis can satisfy
 28 essential requirements (i.e., nonlinearity and short-term memory) for reservoir computing.
 29 This study indicates that the asymmetry and hysteresis contribute to such performance.
 30 Furthermore, the performance can be improved by modulation of these features appearing
 31 in the device through material engineering to optimize its response speed.⁶⁶⁾

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Figure Captions

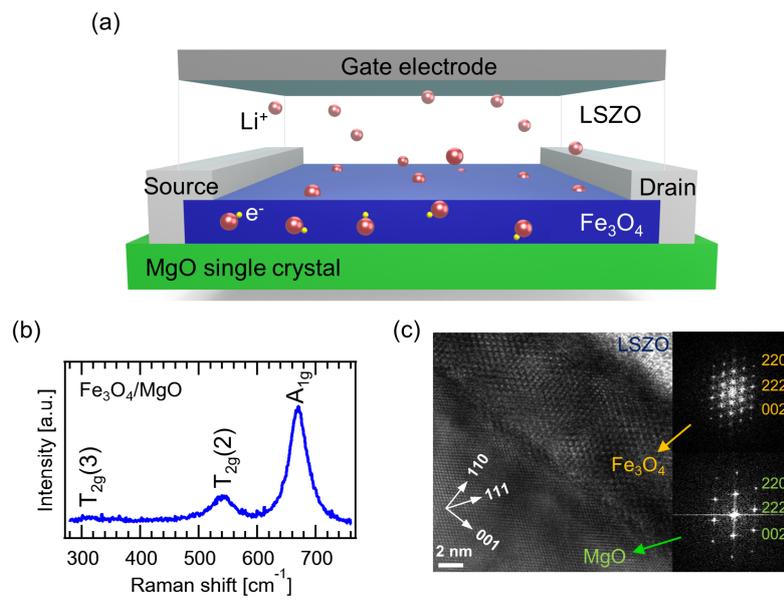
Fig. 1. (a) A schematic illustration of a fabricated all-solid-state redox device. LSZO denotes a $\text{Li}_2\text{O-SiO}_2\text{-ZrO}_2$ thin film. (b) A Raman spectrum of a Fe_3O_4 thin film deposited on MgO single crystal. (c) TEM image and its fast Fourier transform of a cross-section of the fabricated device shown in (a).

Fig. 2. (a) Normalized drain current I_D variation at various gate voltage V_G , measured with sweeping V_G . The sweeping rate is fixed at 0.9 mV/sec. (b) A part of a unit cell of Fe_3O_4 and spin configuration in 3d orbits of Fe_{8a} and Fe_{16d} . The red arrow denotes doped down spin with Li-ion (Li^+) insertion into the lattice.

Fig. 3. (a) A measurement configuration of an all-solid-state redox device to acquire voltage drop in Fe_3O_4 thin film V_{XX} . S and D denote source and drain electrodes. (b) V_{XX} response for a voltage pulse at a time step k , corresponding to a region colored gray surrounded by a dashed line. Relaxation time variations at various k in (c) pulse-on duration and (d) pulse-off duration.

Fig. 4. (a) V_{XX} response at the cropped region ranging from 750 (k_{39}) to 850 (k_{42}). Red (Blue) arrows denote V_{XX} amplitude and V_G amplitude in pulse-on (pulse-off) duration. (b) Relaxation time variation at the region ranging from k_{39} to k_{42} . (c) Pulse period dependence of relaxation time at various time steps. (d) Schematic principle of transition speed variation of redox reaction induced by pulse-on and pulse-off.

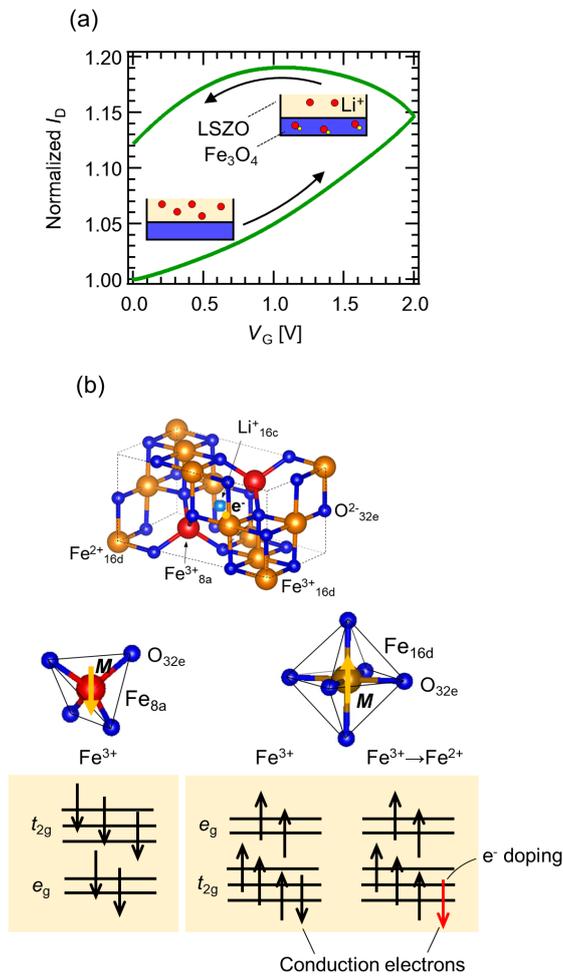
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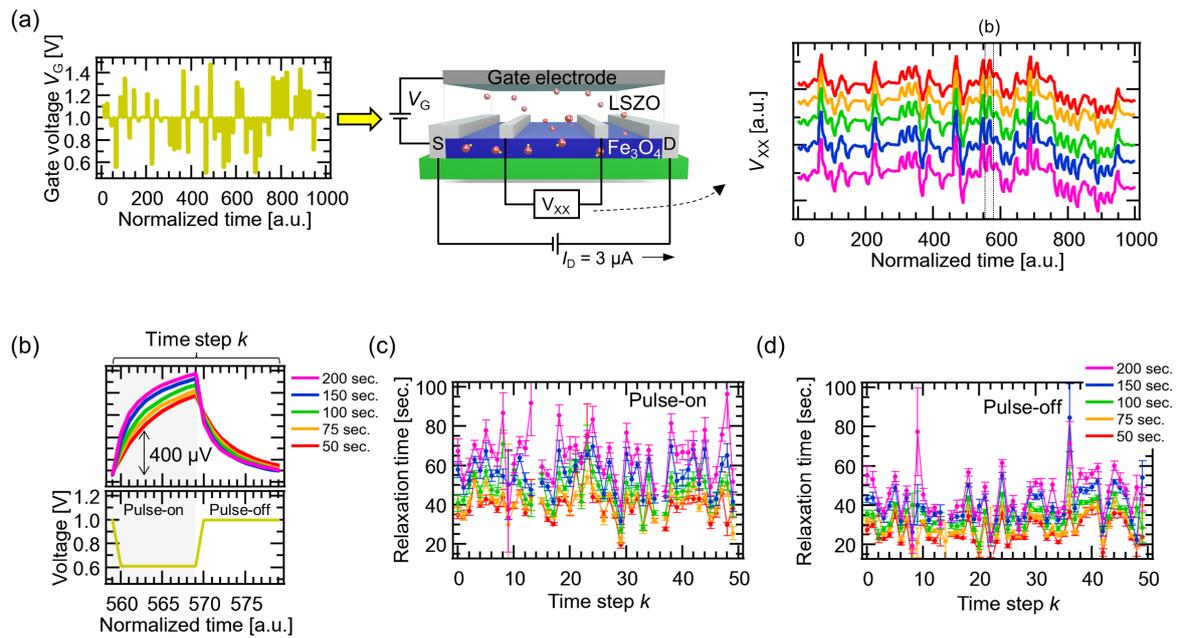
Fig.1.

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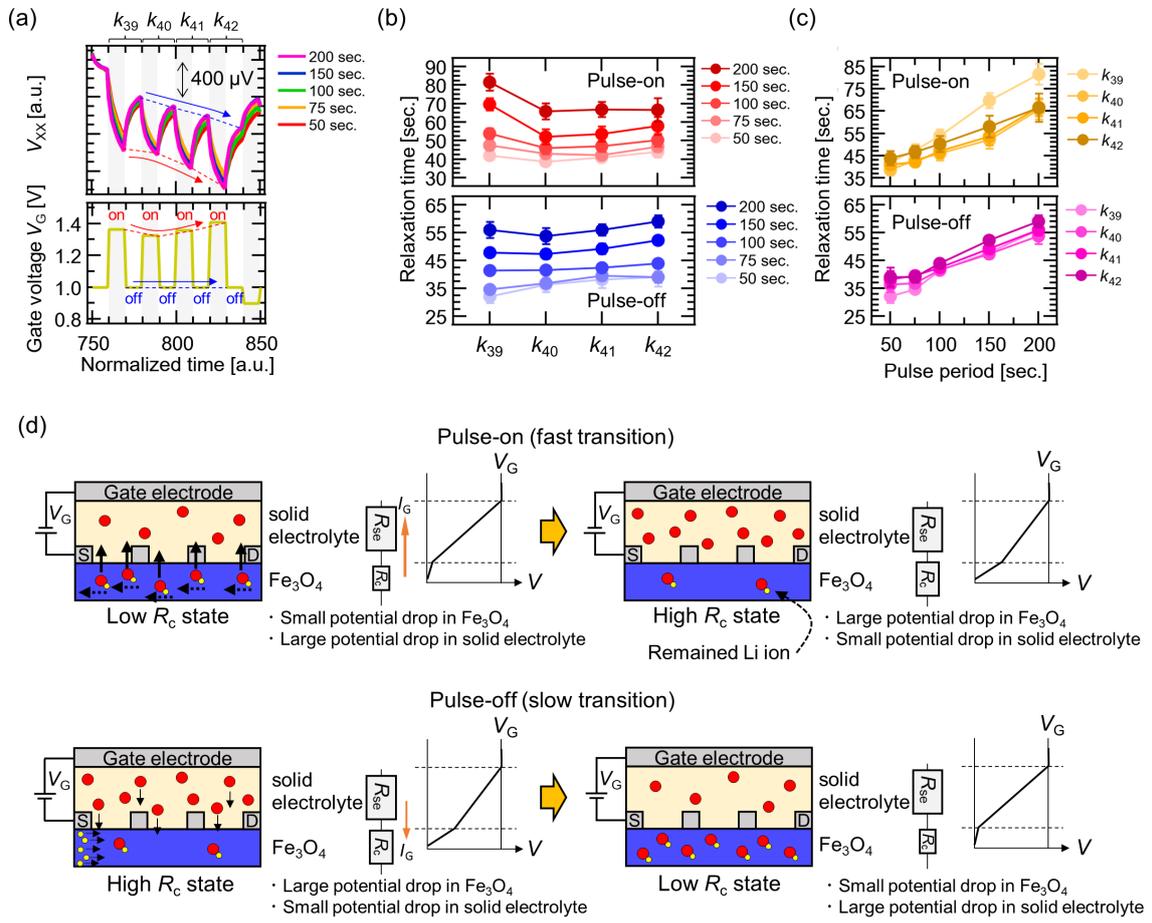
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Fig. 3

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Fig.4